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PATENT
0020-4931P

IN THE U.S. PATENT AND TRADEMARK OFFICE

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| Applicant: | Masayuki OHTA | Conf.: | 8299 |
| Appl. No.: | 09/994,673 | Group: | 1762 |
| Filed: | November 28, 2001 | Examiner: | Timothy H. MEEKS |
| For: | METHOD FOR EVENLY COATING SEMICONDUCTOR LASER END FACES AND FRAME USED IN THE METHOD | | |

#5
Freda
7/14/03

REPLY TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

July 10, 2003

Sir:

In reply to the Restriction Requirement dated June 13, 2003, the following remarks are respectfully submitted in connection with the above-identified application.

REMARKS

Claims 1-4 remain in the present application.

In the Examiner's Office Action, the Examiner issued a Restriction Requirement, and requested that Applicant elect one of the four following groups for prosecution in connection with the present application. The four groups are as follows:

Group I, represented by claim 1 allegedly drawn to a first method of coating,

Group II, represented by claim 2, allegedly drawn to a second method of coating,

Group III, represented by claim 3, allegedly drawn to a third method of coating, or

Group IV, represented by claim 4, allegedly drawn to an apparatus.